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To: Commissioner for Patents
Art Unit 2812

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From: Ira Matsil

Pages: 2

Applicant: Chen, *et al.*

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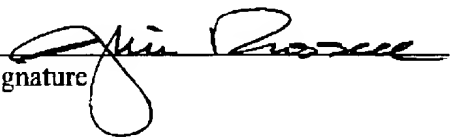
Examiner: Raevis, Robert R.

For: Direct, Non-Destructive Measurement of Recess Depth in a Wafer

Certificate of Transmission under 37 C.F.R. § 1.8

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